

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Koichiro TANAKA, et al.) Group Art Unit: 3742
Application No. 10/769,820) Examiner: Samuel M. Heinrich
Filed: February 3, 2004) Confirmation No. 9528
For: LASER IRRADIATION STAGE, LASER)
IRRADIATION OPTICAL SYSTEM, LASER)
IRRADIATION APPARATUS, LASER)
IRRADIATION METHOD, AND METHOD OF)
MANUFACTURING A SEMICONDUCTOR)
DEVICE

SUBMISSION OF FORMAL DRAWINGS

MAILSTOP: Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Submitted herewith are four (4) sheets of formal drawings, consisting of Figures 4A, 4B,
6, 7A, 7B, 8A and 8B, for filing in the subject application.

Respectfully submitted,

By: /Jeffrey L. Costellia, Reg. No. 35,483/
Jeffrey L. Costellia

NIXON PEABODY LLP
CUSTOMER NO.: 22204
401 9th Street, N.W., Suite 900
Washington, DC 20004
Tel: 202-585-8000
Fax: 202-585-8080